



Attorney Docket No. UMC-96-279 CON2
Client Matter No. 81848.0016.002

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/991,196	Confirmation No.: 3908
Application of: LIU, Chih-Chien <i>et al</i>	Customer No.: 25235
Filed: November 20, 2001	
Art Unit: 1711	
Examiner: SERGENT, R.A.	
Attorney Docket No. UMC-96-279 CON2	
For: HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	

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RESPONSE UNDER 37 C.F.R. § 1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

An Office Action was mailed in the above case June 25, 2003. Please reconsider the case in light of the following remarks.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.

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